

Attorney Docket No. FUJ 99228 CIP Client Matter No. 80458.0011 Express Mail No.: EV035493725US

Examiner: Lee, Hsien Ming

Confirmation No.: 9686

Art Unit: 2823

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Katsuyoshi Matsuura et al.

Serial No. 09/551,233

Filed: April 17, 2000

SEMICONDUCTOR DEVICE HAVING A FERROELECTRIC CAPACITOR AND A FABRICATION PROCESS THEREOF

For:

AMENDMENT AND RESPONSE PURSUANT TO OFFICE ACTION **DATED JUNE 19, 2002**

BOX FEE AMENDMENT Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

In response to the office communication mailed June 19, 2002, please amend the application as follows:

IN THE CLAIMS:

Please cancel claim 13, without prejudice.

Please amend claims 12, 14, and 15 to read-as-follows:

12. (Amended) A method of fabricating a semiconductor device having a ferroelectric capacitor, comprising the steps of:

forming an active device element by a substrate;

forming an insulation film over said substrate to cover said active device element;